## Supporting Information

# A judicious hetero-dopants injection and abstraction of Co<sub>3</sub>O<sub>4</sub> catalyst for efficient methane oxidation

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#### **Text S1 Catalysts characterizations**

Field emission scanning electron microscope (SEM) and energy dispersion spectrometer (EDS) images were obtained on JEOL JSM-7800F, and transmission electron microscope (TEM) images were obtained on a JEOL JEM-2100. X-ray diffraction (XRD) pattern was recorded on a Rigaku Ultima IV with Cu-Ka radiation  $(\lambda = 0.15418)$ . Inductively Coupled Plasma (ICP) was tested on Agilent ICP-OES/730. N2 sorption experiment was performed on Quantachrome Autosorb iQ3 at 77 K. The specific surface area was calculated using the Brunauer-Emmett-Teller (BET) method, the pore size distribution was estimated with Density Functional Theory (DFT) method and X-ray photo-electron spectroscopy (XPS) was obtained on a PHI5000 Versaprobe III XPS spectrometer with an Al Ka X-ray source (1486.6 eV) and the indepth XPS analysis were obtained by etching the surface with argon ions. Electron paramagnetic resonance (EPR) measurements were recorded on an FA-200 (JES) electron paramagnetic resonance spectrometer. Raman spectra were recorded on a Renishaw in Via Plus Micro-Raman spectroscopy system equipped with a 50 mW DPSS laser at 532 nm. H<sub>2</sub> temperature-programmed reduction (H<sub>2</sub>-TPR) were estimated using a Quantachrome Chembet Pulsar analyzer. 30 mg of sample was pretreated with Ar atmosphere at 200 °C for 30 min to remove the adsorbed volatiles, and then the sample was cooled to 50 °C. TPR curve was recorded with 5% hydrogen (balanced with Ar) at a flow rate of 100 mL·min<sup>-1</sup> and a heating rate of 10 °C·min<sup>-1</sup>. In-situ diffuse reflectance infrared Fourier transform spectroscopy (DRIFTs) was performed on a NICOLET iS50 infrared spectrometer (Thermo Fisher Scientific). After the catalyst was deposited in the in-situ cell, 10 mL·min<sup>-1</sup> of argon flow was introduced and maintained at 300 °C for 60 min, then the temperature was lowered from 300 °C to 50 °C. After background collection, the reaction feed containing 2 *vol*.% CH<sub>4</sub>, 20 *vol*.% O<sub>2</sub> and is balanced with Ar was additionally introduced into the cell with the temperature gradually raised to 450 °C. In the meantime, IR spectra acquisition was conducted under 50 °C, 150 °C, 250 °C, 350 °C and 450 °C after the temperature stabilization.

#### Text S2 Density functional theory (DFT) calculation method

The plane-wave-based periodic DFT method was carried out with the Vienna *ab initio* simulation package (VASP).<sup>1,2</sup> The projector augmented wave (PAW) setups was used to describe the electron-ion interactions, while the exchange and correlation energy were selected to be parameterized by the Perdew, Burke and Engerhoff (PBE) functional.<sup>3,4</sup> Based on XRD and TEM results, the Co<sub>3</sub>O<sub>4</sub> (311) was modeled using a four-layer periodic slabs. Cr doped Co<sub>3</sub>O<sub>4</sub> (311) facet was modeled with three Co atoms substituted by three Cr atoms, which was designated as Cr-Co<sub>3</sub>O<sub>4</sub> (311). The Cr doped Co<sub>3</sub>O<sub>4</sub> (311) facet with Cr vacancy was built by removing one surface Cr atoms, which was named as Cr-Co<sub>3</sub>O<sub>4</sub>-OH (311). The oxygen vacancy formation energy (E (O<sub>y</sub>)) on different models were defined by the following formulas:

$$E(O_v) = E(Cr-Co_3O_{4-x}) + 1/2E(O_2) - E(Cr-Co_3O_4)$$

Where  $E(Cr-Co_3O_{4-x})$  represents the energy of Cr doped Co<sub>3</sub>O<sub>4</sub> (311) slab model with oxygen vacancy (surface oxygen vacancy was created by removing one O atom.),  $E(O_2)$  corresponds to the energy of O<sub>2</sub> gas molecule, and  $E(Cr-Co_3O_4)$  is the energy of Cr doped Co<sub>3</sub>O<sub>4</sub> slab model.



Fig. S1 (a) SEM, (b) TEM and (c) HR-TEM image of Co<sub>3</sub>O<sub>4</sub>.



Fig. S2 (a) SEM image, and EDS elemental mapping of (b) O, (c) Co and (d) Cr for Cr-Co<sub>3</sub>O<sub>4</sub>.



Fig.S3 EPR spectra for Cr-Co<sub>3</sub>O<sub>4</sub> and Cr-Co<sub>3</sub>O<sub>4</sub>-OH.



Fig. S4 CH<sub>4</sub> oxidation performances (reaction condition: 2 *vol.*% of CH<sub>4</sub>, 20 *vol.*% O<sub>2</sub>, Ar as balance gas, flow velocity = 66 mL·min<sup>-1</sup>, WHSV = 40,000 mL·g<sup>-1</sup>·h<sup>-1</sup>) of (a) Co<sub>3</sub>O<sub>4</sub> with different Cr doping amounts and (b) Cr-Co<sub>3</sub>O<sub>4</sub> that etched in alkali for different time.



Fig. S5 CH<sub>4</sub> oxidation performances (reaction condition: 2 *vol.*% of CH<sub>4</sub>, 20 *vol.*% O<sub>2</sub>, Ar as balance gas, flow velocity = 66 mL·min<sup>-1</sup>, WHSV = 40,000 mL·g<sup>-1</sup>·h<sup>-1</sup>) of  $Co_3O_4$  and  $Co_3O_4$ -OH.



Fig. S6 Stability test of Cr-Co<sub>3</sub>O<sub>4</sub>-OH at reaction temperature of T<sub>90</sub> (327 °C) and T<sub>50</sub> (278 °C) (reaction condition: 2 *vol.*% of CH<sub>4</sub>, 20 *vol.*% O<sub>2</sub>, Ar as balance gas, flow velocity = 66 mL·min<sup>-1</sup>, WHSV = 40,000 mL·g<sup>-1</sup>·h<sup>-1</sup>).



Fig. S7 TEM images of Cr-Co<sub>3</sub>O<sub>4</sub>-OH, Cr-Co<sub>3</sub>O<sub>4</sub>-OH-T<sub>50</sub> and Cr-Co<sub>3</sub>O<sub>4</sub>-OH-T<sub>90</sub>.



Fig. S8 (a) XRD patterns, (b)  $N_2$  sorption isotherm and (c) NL-DFT pore size distribution for the catalysts of Cr-Co<sub>3</sub>O<sub>4</sub>-OH, Cr-Co<sub>3</sub>O<sub>4</sub>-OH-T<sub>50</sub> and Cr-Co<sub>3</sub>O<sub>4</sub>-OH-T<sub>90</sub>.



Fig. S9 O 1s XPS spectra for Cr-Co<sub>3</sub>O<sub>4</sub>-OH, Cr-Co<sub>3</sub>O<sub>4</sub>-OH-T<sub>50</sub> and Cr-Co<sub>3</sub>O<sub>4</sub>-OH-T<sub>90</sub>.

Table S1 Cr content of Cr-Co<sub>3</sub>O<sub>4</sub> at different Ar ions etching time by XPS.

location	etching time	

	0 min	10 min
1	4.06 wt.%	2.05 wt.%
2	4.24 <i>wt</i> .%	2.16 <i>wt</i> .%
3	4.56 <i>wt</i> .%	1.94 wt.%

Table S2 Cr content of Cr-Co<sub>3</sub>O<sub>4</sub>-OH at different Ar ions etching time by XPS.

location —	etching	g time
	0 min	10 min
1	2.63 wt.%	2.09 wt.%
2	2.49 <i>wt</i> .%	2.04 wt.%
3	2.13 <i>wt</i> .%	2.15 wt.%

Table S3 Crystallite size, specific surface area and surface information of the catalysts.

Sample	Crystallite size <sup>a</sup> (nm)	Specific surface area <sup>b</sup> (m <sup>2</sup> ·g <sup>-1</sup> )	O <sub>v</sub> (%) °
Cr-Co <sub>3</sub> O <sub>4</sub> -OH	18.2	67.4	51.6
Cr-Co <sub>3</sub> O <sub>4</sub> -OH-T <sub>90</sub>	21.9	23.5	42.6
Cr-Co <sub>3</sub> O <sub>4</sub> -OH-T <sub>50</sub>	18.7	37.4	42.9

<sup>a</sup> Crystallite size calculated by Scherrer formula.

<sup>b</sup> Pore volume calculated at  $P/P_0$  of 0.99.

<sup>c</sup> Data determined from XPS results.

### References

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